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Facsimile No. (41-22)338-8270

Amendment of the claims under Article 19(1) (Rule 46)

International Application No. : PCT/JP2005/010790
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Agent's File reference : P05328800

Dear Sir,

The Applicant, who received the International Search Report relating to the above-identified International Application transmitted on 04.10.2005, hereby files amendment under Article 19(1) as in the attached sheets.

We hereby would like to amend the claim 1.
The claims 2-27 are retained unchanged.

Very truly yours,

Takamatsu Takeshi
TAKAMATSU Takeshi

Attachment:
(1) Amendment under Article 19(1) 1 sheet

CLAIMS

1. (Amended) An electromechanical signal selection device comprising:

a micro-vibrator which can be excited by an input signal; and

a post for retaining the micro-vibrator,

wherein the micro-vibrator can generate a change in physical property due to excitation so as to select a selected signal.

2. The electromechanical signal selection device according to claim 1, wherein the micro-vibrator comprises a material whose physical property is changed in accordance with a structural change.

3. The electromechanical signal selection device according to claim 1 or 2, wherein the physical property is an electric conduction characteristic.

4. The electromechanical signal selection device according to claim 1, wherein the micro-vibrator is retained by an electrode placed on the post.

5. The electromechanical signal selection device according

to claim 4, wherein a bonded surface between the electrode and the micro-vibrator is located at a distance from the post.

6. The electromechanical signal selection device according to claim 1, wherein the post comprises a structure having lower rigidity than that of the micro-vibrator.

7. The electromechanical signal selection device according to claim 1, wherein the micro-vibrator comprises a multilayer structure of at least two layers including a material layer generating the change in physical property and a conductor layer.

8. The electromechanical signal selection device according to claim 7,

wherein the conductor is formed to be linear, and

wherein the material layer generating the change in physical property is formed around the linear conductor layer.

9. The electromechanical signal selection device according to claim 7, wherein the material layer generating the change in physical property is formed on the side where an electric field of a signal is concentrated.